

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:) Confirmation No.: 9528
Koichirto TANAKA)
Serial No. 10/769,820) Examiner: Samuel M. Heinrich
Filed: February 3, 2004) Group Art Unit: 3742
For: LASER IRRADIATION STAGE, LASER) Date: July 17, 2009
IRRADIATION OPTICAL SYSTEM,)
LASER IRRADIATION APPARATUS,)
LASER IRRADIATION METHOD, AND)
METHOD OF MANUFACTURING A)
SEMICONDUCTOR DEVICE)

MAIL STOP AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT UNDER 37 C.F.R. § 1.114

In response to the Final Office Action mailed April 17, 2009, please amend the above-captioned application, as follows:

Amendments to the Claims are reflected in the listing of claims in this paper.

Remarks follow the amendment section of this paper.